



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Florence Eschbach et al. Art Unit: Unknown  
Serial No.: 10/649,355 Examiner: Unknown  
Filed : August 26, 2003 Assignee: Intel Corporation

Title : MOUNTING A PELLICLE TO A FRAME

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

This filing is being made before the receipt of a first Office action on the merits. No fee is required.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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Respectfully submitted,

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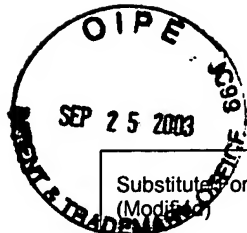
 /BY  
ALEX CHEN  
REG. NO. 45,591

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Scott C. Harris  
Reg. No. 32,030  
Attorneys for Intel Corporation

Fish & Richardson P.C.  
PTO Customer No. 20985  
4350 La Jolla Village Drive, Suite 500  
San Diego, CA 92122  
Telephone: (858) 678-5070  
Facsimile: (858) 678-5099

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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. Intel 10559-865001 / P17313	Application No. 10/649,355
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)  (37 CFR §1.98(b))      IDS filed 09/22/2003		Applicant Florence Eschbach et al.	
		Filing Date August 26, 2003	Group Art Unit

**U.S. Patent Documents**

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						

**Foreign Patent Documents or Published Foreign Patent Applications**

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AH							
	AI							
	AJ							
	AK							
	AL							

**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
	AM	D.W. Van Krevelen, with the collaboration of P.J. Hoftyzer; "Properties of Polymers, Their Estimation and Correlation with Chemical Structure," Second, completely revised edition; 1976, Elsevier Scientific Publishing Company, Amsterdam – Oxford – New York
	AN	Oshima et al.; Radiation Physics and Chemistry, "Chemical structure and physical properties of radiation-induced crosslinking of polytetrafluoroethylene"; © 2001 Elsevier Science Ltd.; <a href="http://www.elsevier.com/locate/radphyschem">www.elsevier.com/locate/radphyschem</a>
	AO	Reu et al.; "Mechanical analysis of hard pellicles for 157 nm lithography," to appear in the Proceedings of the 2001 SPIE Symposium on Optical Microlithography XIV, Vol. 4346, 2001; UW Computational Mechanics Center, University of Wisconsin, Madison, WI 53706; Intel Corporation, Santa Clara, CA 95052
	AP	Kozeki et al.; "Longevity of 193nm/ArF Excimer Pellicle; April 26, 2001; Mitsui Chemicals, Inc., Pellicles Dept.
	AQ	Shu et al.; "Hard Pellicle Study for 157-nm Lithography"; Preprint, to appear in the Proceedings of Photomask Japan, 2002

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	